

"GETTER SYSTEM FOR PURIFYING THE WORK ATMOSPHERE IN THE
PROCESSES OF PHYSICAL VAPOR DEPOSITION"

ABSTRACT

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A system is disclosed formed of one or more getter devices in form of sintered bodies of getter powders or deposits of getter material onto a metal support, to be arranged in the work area of process chambers for the deposition of thin layers of metallic or ceramic materials from vapors or plasmas for-purifying the

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gaseous atmosphere contained in that area.

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